

Rate capability and magnetic field tolerance measurements of fast timing microchannel plate photodetectors

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Abstract

Microchannel plate photodetectors provide both picosecond time resolution and sub-millimeter position resolution, they are attractive sensors for particle identification detectors of future US Electron Ion Collider. We have tested the rate capability and magnetic field tolerance of 6×6 cm² microchannel plate photodetectors fabricated at Argonne National Laboratory. The microchannel plate photodetector is designed of low-cost all-glass vacuum package with a chevron pair stack of “next generation” microchannel plates functionalized by atomic layer deposition. The rate capability test was performed with Fermilab 120 GeV primary proton beam, and the magnetic field tolerance test was performed on a solenoid magnetic facility with tunable magnetic field strength up to 4 Tesla. The gain of measured microchannel plate photodetector is stable up to 75 kHz/cm², and varies depending on the applied magnetic field strength and rotation angle relative to the magnetic field direction.

Index terms— Fast timing, Microchannel plate, Photodetector, Electron Ion Collider, Particle identification detector, Rate capability, Magnetic field, Rotation angle.

1. Introduction

The world’s first Electron Ion Collider (EIC) [1] has been recommended as the highest priority for a new facility construction in the U.S [2]. This unique facility will explore several features of the strong force and QCD through mapping the partons, quarks and gluons, content of nucleons and nuclei up to uranium. Several detector concepts are proposed and designed for the EIC at Argonne National Laboratory (ANL), Brookhaven National Laboratory (BNL), Thomas Jefferson National Accelerator Facility (JLab) and some other institutes, with slightly different layout. For all these EIC detector designs, excellent particle identification (PID), ($e/\pi/K/p$) separations over a wide range of momentum, is essential for the proposed measurements, such as semi-inclusive deep inelastic scattering and exclusive deeply virtual Compton scattering. Time-of-flight systems and imaging Čerenkov detectors (RICH, DIRC) [3, 4, 5] are proposed and studied, calling for large area, low cost photon sensors with high spatial resolution, high rate capability, radiation tolerance, magnetic field tolerance and picosecond timing resolution.

Microchannel plate (MCP) photodetectors are compact photon sensors, usually with an internal chevron pair stack of MCPs, providing both high spatial and temporal resolution in a vacuum package. The Large Area Picosecond Photodetector (LAPPDTM) is the world largest MCP

based photodetector with an active area of 20×20 cm² [6]. It is designed of a modular all-glass detector package with the “next generation” MCPs produced by applying resistive and emissive coatings to borosilicate glass capillary array (GCA) substrates through atomic layer deposition (ALD) process. The all-glass design and low-cost “next generation” MCPs provide great advantages to reduce the LAPPDTM product cost per area compared to other MCP based photodetectors currently available. As a collaborator of the LAPPD project [7], we have built a MCP photodetector fabrication system [8] at Argonne National Laboratory to fabricate 6×6 cm² MCP photodetectors with LAPPD design. The fabricated MCP photodetectors were provided to several experiments for early test and adaption of LAPPD detector. The MCP photodetector fabrication system also serves as a R&D platform for LAPPD package design validation and optimization. Several 6×6 cm² MCP photodetectors with standard LAPPD design were successfully fabricated and tested [9, 10, 11], exhibiting high gain over 10^7 , overall time resolution of 35 ps and position resolution better than 1 mm. The excellent performance of these 6×6 cm² MCP photodetectors shows that the low-cost LAPPDTM detector is a promising candidate for EIC PID photo sensors. Performance tests of the MCP photodetectors in high rate, high radiation damage and high magnetic field environments are required to further validate the application of LAPPDTM detectors as EIC PID photo sensors.

In this paper, we describe the current design of 6×6 cm² MCP photodetectors fabricated at Argonne National Laboratory, report recent results on the performance tests of these 6×6 cm² MCP photodetectors in high rate environment and high magnetic field environment. The direc-

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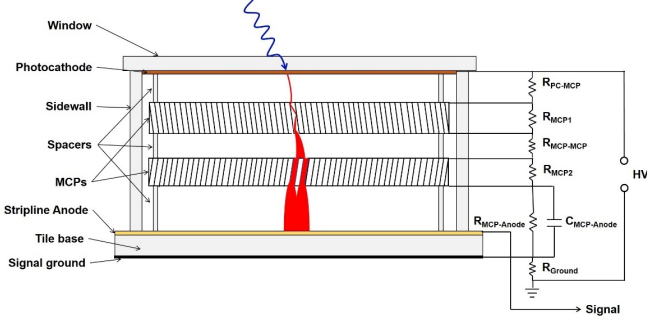


Figure 1: Schematic of MCP-based photodetector assembly (not to scale) and the electrical circuit diagram. External connections to the top and bottom surfaces of the two MCPs are through ultra-thin metal shims (not shown) to special extra strip lines on the tile base. The circuit diagram shows connections through side wall in a simplified format.

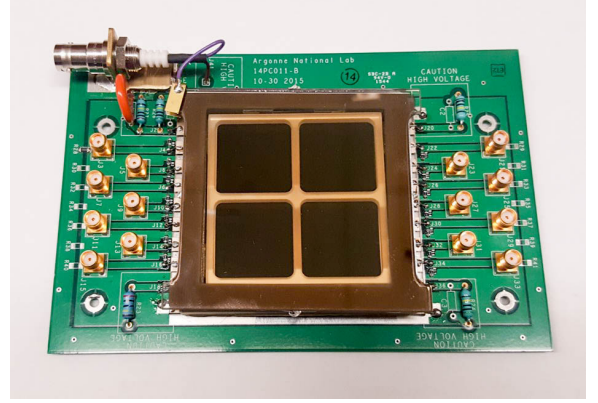


Figure 2: Completed MCP-based photodetector attached to a circuit board, providing firm electrical connections.

tion on further optimization of the LAPPDTM design for EIC PID application is also addressed at the end of this paper.

2. Design of the MCP-based photodetector assembly

Current design of the 6×6 cm² MCP photodetector is developed from the original LAPPD internal resistor chain design [11], similar to the current standard design of commercial LAPPDTM detectors [12]. Fig. 1 shows a schematic design (not to scale) of current MCP-based photodetector assembly and the electrical circuit diagram.

The MCP photodetector is an all glass body assembly, consists of glass base window, top window, side wall, three grid spacers and two MCPs. The sidewall is frit bonded onto the base window, with silver stripline anodes printed, leading the signals and high voltage connections to outside. Grid spacers are placed between anode and MCPs and top window as insulators to separate these components, they also hold these internal components in place in the vacuum assembly. Four ultra-thin metal shims are applied at the top and bottom surfaces of the two MCPs to lead the electrical connection to external connections, detailed circuit connection inside the vacuum package is described in reference [13]. This independent bias-voltage design provides advantage of individually controlling and fine tuning of the bias voltage for each MCP. Bialkali photocathode is deposited on the inside surface of the top window, and an indium seal is made between the top window and the sidewall through a low temperature thermo-compression sealing process to form a hermetic vacuum detector package. The completed MCP-based photodetector is attached to a custom-made circuit board, providing a permanent mount and firm electrical connections as shown in Fig. 2. External electrical connections for both signal and high voltage are inserted into the external resistor connections, to serve as high voltage divider, ensuring both MCPs work

at an independently optimized high voltage for best performance. Additional capacitors may also be added across the resistor divider for better signal waveform.

The microchannel plates used in the 6×6 cm² MCP photodetector are diced from the “next generation” large area (20×20 cm²) MCPs [6, 12], the world largest commercially available MCPs. These “next generation” MCPs are produced through a glass drawing process and functionalized through atomic layer deposition, completely different from the production of traditional leaded glass MCPs. The glass drawing process uses borosilicate glass as tube materials, which is considerably less expensive than the leaded glass and eliminates the chemical etching process required in traditional method, making it much more cost-effective for MCP production. Here, we use standard borosilicate glass MCPs with $20 \mu\text{m}$ pore size, 60:1 L/d (pore length to diameter) ratio and 80 bias angle relative to the MCP surface normal. The two MCPs are placed as the “chevron” configuration in the vacuum package, which reversed the bias angle to -8° .

3. Rate capability measurement

The rate capability of MCP-based photodetectors is one of the most critical parameters for applications in high luminosity environment, such as EIC. Due to the high resistive layer coating on ALD functionalized MCPs, the current in the MCP pores may not flow off fast enough when the MCP-based detector is exposed to high particle rates. This effect may cause severe charge saturation, reduce the gain of the MCP-based photodetector and limit the detector performance.

We investigated the rate capability of the 6×6 cm² MCP-based photodetectors with 120 GeV/c primary proton beam at the Fermilab Test Beam Facility (FTBF). The beam was delivered as a slow spill with a 4 s duration once per minute with a maximum intensity of 10^5 particles per spill. The beam shape is circular with a diameter of 6 mm and a gaussian density profile. The beam intensity was close to a constant during each spill period. On

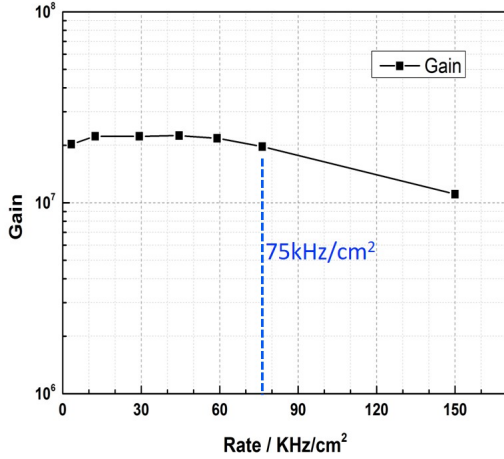


Figure 3: Gain of MCP-based photodetector as a function of the 120 GeV/c proton beam flux. The gain of the detector is stable up to beam flux of 75 kHz/cm², and the gain is still over 10⁷ at 150 kHz/cm².

the beamline, the 120 GeV/c incident proton beam was monitored by an upstream multiwire proportional counter to see the beam profile. Three plastic scintillators in coincidence were used as a trigger and to count the number of incident proton. A light-tight dark box was designed to hold the MCP-based photodetector in the beam path with the detector surface facing the beam direction. High voltage was applied to the MCPs through external resistor voltage divider, and signals from the strip lines were read out through the DT5742 desktop digitizer [14] produced by CAEN (Costruzioni Apparecchiature Elettroniche Nucleari S.p.A.) with a sampling rate of 5 GS/s. The digitizer is based on the switched capacitor array DRS4 (Domino Ring Sampler) chip [15] and have 16 analog input channels and 1 additional analog input for fast trigger.

During our experiment, the 120 GeV/c proton beam intensity was tuned to vary from 500 to 40,000 particles per spill. The beam rate was calculated using the number of triggers per spill and was corrected for the size of the beam spot by reconstructing the beam profile. The calculated beam rate varies from 3 to 150 kHz/cm² corresponding to the monitored beam particle intensity. Fig. 3 shows the gain of the MCP-based photodetector measured as a function of the beam rate. The measured gain of the investigated detector is stable up to a beam flux of 75 kHz/cm² and still over 10⁷ when the beam flux reaches 150 kHz/cm². Such a high rate capability of the MCP-based photodetector will be sufficient for EIC PID detectors at the proposed energies of the beams.

4. Magnetic field tolerance measurement

In the EIC detectors, solenoid magnet with field strength of 1.5 Tesla are proposed. The imaging Čerenkov detec-

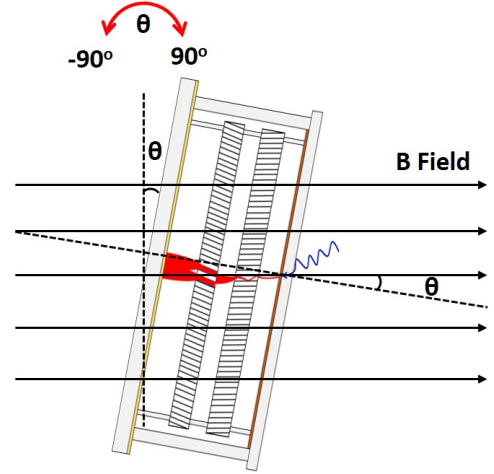


Figure 4: Schematic of the rotation of MCP-based photodetector with angle θ relative to the magnetic field direction during the measurement.

tors (RICH, DIRC) and time-of-flight systems are designed to cover the area of the barrel and end caps for charged particle ($\pi/K/p$) separations. This compact design requires the photo sensors working properly in a harsh environment with magnetic field strength up to 1.5 Tesla.

At Argonne National Laboratory, a decommissioned superconducting magnet from a magnetic resonance imaging (MRI) scanner was acquired to test instruments for the muon g-2 experiment [16]. The magnet provides a large bore with a diameter of 68 cm and a very homogenous field (7 ppb/cm), the magnitude of the magnetic field is tunable up to 4 Tesla. We have built a characterization system compatible with the solenoid magnet to test the performance of the 6×6 cm² MCP-based photodetector in strong magnetic field environment. The MCP photodetector was fixed in a custom built non-magnetic, light-tight dark box. The dark box was held on a test platform with the detector surface normal to the direction of magnetic field. The position of the dark box was adjusted so that the center of the MCP photodetector is well aligned with the center of the solenoid magnet. A rotation mechanism was also integrated with the system, allowing rotation of the MCP-based photodetector with angle θ as shown in Fig. 4 (not to scale). A 405 nm light-emitting diode (LED) was used as the light source and introduced to the surface of the MCP photodetector through an optical fiber. High voltage was applied to the MCPs from a supply with variable voltage control, and signals from the strip lines were readout through CAEN DT5742 desktop digitizer.

4.1. Magnetic field strength dependence

The dependence of the MCP photodetector performance on the magnetic field strength was done at rotation angle $\theta = 0^\circ$, i.e., the direction of the magnetic field is normal to the surface of the MCP-based photodetector. We measured the gain of the investigated MCP photodetector

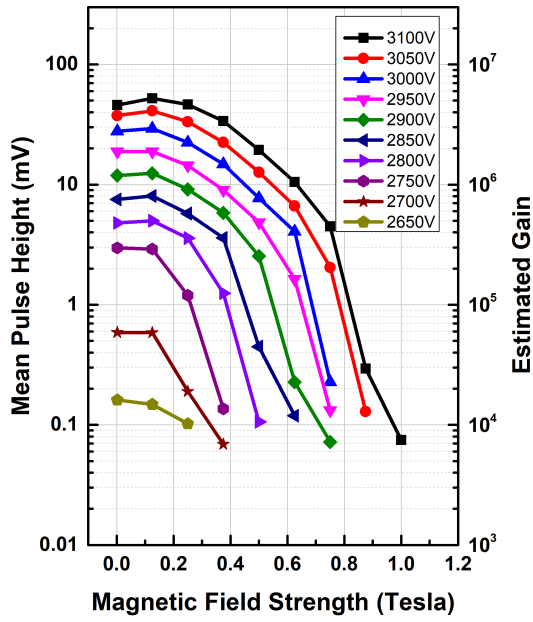


Figure 5: Dependence of the MCP-based photodetector gain on the magnetic field strength at different bias voltages.

in various magnetic field environment with different bias voltages, the results are plotted in Fig. 5. The gain is calculated based on integrated charge in pulse normalized to single photoelectron. At a fixed bias high voltage, the gain of MCP photodetector increases slightly as the magnetic field strength increases to 0.2 T, and starts to decrease as the magnetic field strength continues to increase, and eventually breaks down at magnetic field strength of ~ 0.8 T. In the same magnetic field environment, the gain of the MCP photodetector increases as the biased high voltage increases. This behavior is similar to our previous measurement of the MCP photodetectors without applying magnetic field.

4.2. Magnetic field angle dependence

The performance of MCP-based photodetector at different angle was also studied by rotating the MCP photodetector along with angle θ relative to the magnetic field direction, as shown in Fig 5. We fixed the biased high voltage at 3000 V on the photodetector and rotated the photodetector from -90° to 90° for a full angle measurement. Fig. 6 shows the gain of MCP photodetector measured as a function of the rotation angle θ at magnetic field strength of 0.5 and 0.25 Tesla respectively. The MCP photodetector almost does not provide detectable signals when $\theta \leq -30^\circ$ or $\theta \geq 30^\circ$. Within $-30^\circ \leq \theta \leq 30^\circ$, there are two gain peaks at $\theta = \pm 8^\circ$, which are due to the “chevron” configuration of two MCPs inside the photodetector. The gain reaches a maximum when the pore of either MCP is well aligned with the magnetic field direction. Meanwhile, the intensities of the two peaks are different, which is due to the different effect from the top and bottom MCPs.

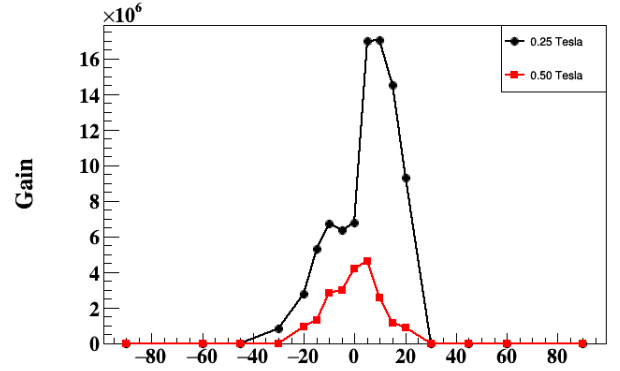


Figure 6: Gain of MCP-based photodetector as a function of rotation angle θ relative to the direction of magnetic field. The two peaks around -8° and 8° indicates the effect due to the 8° bias angle of the MCPs. Note that the intensities of these two peaks are not the same due to the different effect from top and bottom MCPs.

4.3. Design optimization of MCP-based photodetector

In EIC experiment, 1.5 Tesla solenoid magnet will be used for tracking charged particles. The magnetic field tolerance requirement varies from detector to detector depending on their distance and direction to the magnet, and is up to 1.5 Tesla. From our measurement, the 6×6 cm² MCP-based photodetector has shown a good magnetic field tolerance up to 0.8 Tesla, comparable to that of current commercially available MCP-PMTs (~ 1.0 T) with similar pore size [17]. Here, we must emphasize that the current LAPPD design is not optimized yet for magnetic field tolerant applications. The distances between the photocathode, MCPs and anode are pretty large in the LAPPD design, e.g., spacings between the photocathode and MCPs are 2 mm and the spacing between the MCP and anode is 3.2 mm [10], these distances should be reduced to minimize the electron transit distance. Meanwhile, MCP photodetectors with smaller pore size MCPs have shown better magnetic field tolerance than the ones with larger pore size MCPs [17, 18, 19]. A redesign of the current LAPPD configuration with smaller pore size (e.g. 10 μ m or even 5 μ m) “next generation” MCPs and reduced distances between the PMT elements would further improve its magnetic field tolerance to the required level.

5. Conclusions

We have described the current design of 6×6 cm² microchannel plate photodetectors with “next generation” MCPs functionalized through atomic layer deposition process. The rate capability and magnetic field tolerance of these photodetectors were tested at Fermilab 120 GeV proton beam and Argonne 4 Tesla magnetic field facility respectively. The photodetectors exhibit stable performance up to 75 kHz/cm² and magnetic field tolerance up to 0.8

Tesla. The magnetic field angle dependence was also measured, showing enhanced performance at $\pm 8^\circ$ tilt angle due to the original MCP 8° bias angle. The magnetic field tolerance of these detectors should be further improved by applying smaller pore size MCPs and redesign the package with reduced distances between the photocathode, MCPs and anode.

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